



Attorney Docket No. 007413-076 *JRW*

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of )  
Michael Steigerwald et al. ) Group Art Unit: 2881  
Application No.: 10/825,240 ) Examiner:  
Filed: April 16, 2004 ) Confirmation No.: 7784  
For: ELECTRON MICROSCOPY SYSTEM, )  
ELECTRON MICROSCOPY METHOD )  
AND FOCUSING SYSTEM FOR )  
CHARGED PARTICLES )

**REQUEST FOR CORRECTED OFFICIAL FILING RECEIPT**

Commissioner for Patents  
Office of Initial Patent Examination  
Customer Service Center  
P.O. Box 1450  
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Sir:

Enclosed is a copy of the Official Filing Receipt marked in red to show correction that is needed. The correction is as follows:

In the Title section, please change "charges" to --charged--.

Also attached is a Supplemental Application Data Sheet reflecting the same change.

Issuance of a corrected Official Filing Receipt is respectfully requested.

Respectfully submitted,

BURNS, DOANE, SWECKER & MATHIS, L.L.P.

Date: August 4, 2004

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## UNITED STATES PATENT AND TRADEMARK OFFICE

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| APPL NO.   | FILING OR 371<br>(c) DATE | ART UNIT | FIL FEE REC'D | ATTY.DOCKET NO | DRAWINGS | TOT CLMS | IND CLMS |
|------------|---------------------------|----------|---------------|----------------|----------|----------|----------|
| 10/825,240 | 04/16/2004                | 2881     | 1682          | 007413-076     | 9        | 42       | 9        |

## CONFIRMATION NO. 7784

21839  
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## FILING RECEIPT



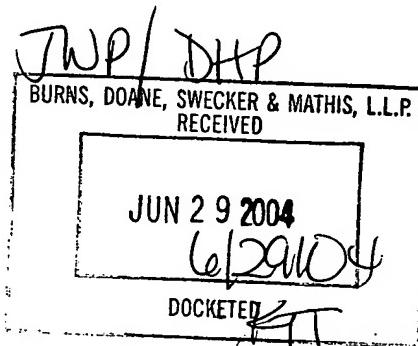
\*OC000000013084671\*

Date Mailed: 06/28/2004

Receipt is acknowledged of this regular Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE, NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. If an error is noted on this Filing Receipt, please write to the Office of Initial Patent Examination's Filing Receipt Corrections, facsimile number 703-746-9195. Please provide a copy of this Filing Receipt with the changes noted thereon. If you received a "Notice to File Missing Parts" for this application, please submit any corrections to this Filing Receipt with your reply to the Notice. When the USPTO processes the reply to the Notice, the USPTO will generate another Filing Receipt incorporating the requested corrections (if appropriate).

## Applicant(s)

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## Assignment For Published Patent Application

LEO Elektronenmikroskopie GmbH, Oberkochen, GERMANY;

## Domestic Priority data as claimed by applicant

## Foreign Applications

GERMANY 10317894.5 04/17/2003

If Required, Foreign Filing License Granted: 06/26/2004

Projected Publication Date: To Be Determined - pending completion of Missing Parts

Non-Publication Request: No

Early Publication Request: No

## Title

Electron microscopy system, electron microscopy method and focusing system for charged particles

charged

7/16/04